

| | L # | Hits | Search Text | DBs | Time Stamp |
|---|-----|------|---|---|------------------|
| 1 | L1 | 8146 | (427/2.1-2.31,488-491,535-539,562-564,569-579).CCLS. | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/24 15:09 |
| 2 | L2 | 3975 | ((plasma (glow electric corona)adj discharg\$4)with(atmospheric adj pressure "1 atm" "1 atmosphere" "736 torr" "736 mmHg" "736 mm Hg" atm)) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/24 15:15 |
| 3 | L3 | 300 | 1 and 2 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/24 15:09 |
| 4 | L4 | 2211 | (427/2.1-2.31).CCLS. | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/24 15:09 |

10/017,193

| | L # | Hits | Search Text | DBs | Time Stamp |
|---|-----|------|--|---|----------------------|
| 5 | L5 | 45 | 3 and(cell protein peptide amino adj acid P15 "P-15" cadherin) <i>missed nucleic acids</i> | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:15 |
| 6 | L6 | 1197 | 4 and(cell protein peptide amino adj acid P15 "P-15" cadherin) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:16 |
| 7 | L7 | 681 | 4 and(plasma (glow electric corona)adj discharg\$4) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:16 |
| 8 | L8 | 519 | 7 and(cell protein peptide amino adj acid P15 "P-15" cadherin) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:17 |

| | L # | Hits | Search Text | DBs | Time Stamp |
|----|-----|------|--|---|----------------------|
| 9 | L9 | 4 | 3 and (laminin fibronectin collagr vitronectin tenascin fibrinogen thrombospondin osteopontin von adj willibrand adj factor sialoprotein) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:20 |
| 10 | L10 | 148 | 7 and (laminin fibronectin collagr vitronectin tenascin fibrinogen thrombospondin osteopontin von adj willibrand adj factor sialoprotein) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:21 |
| 11 | L11 | 147 | 7 and (collagen) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:21 |
| 12 | L12 | 4 | 3 and (collagen) | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:22 |

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| | L # | Hits | Search Text | DBs | Time Stamp |
|----|-----|------|-------------|---|----------------------|
| 13 | L13 | 3 | 12 and 9 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:22 |
| 14 | L14 | 5 | 12 or 9 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:24 |
| 15 | L15 | 211 | 10 or 11 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:23 |
| 16 | L16 | 84 | 10 and 11 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:23 |

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| | L # | Hits | Search Text | DBs | Time Stamp |
|----|-----|------|---------------|---|----------------------|
| 17 | L17 | 45 | 12 or 9 or 5 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:24 |
| 18 | L18 | 5 | 12 or 9 and 5 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:24 |
| 19 | L19 | 40 | 17 not 18 | USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB | 2003/06/2 4 15:25 |

20 L20 (19) 19 + (PTFE or poly tetra fluoroethylene or -----)
 21 (34) 24 not 20

L18

6

these

11/12/98

pull
103 types

pull

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|---|--------------------|------------|--|------------|------------------------------|
| 1 | US 2003011 3478 A1 | 2003061 9 | Surface coating method and coated device | 427/535 | Dang, Mai Huong et al. |
| 2 | US 2003000 8397 A1 | 2003010 9 | Coupled peptide s | 435/402 | Beumer, Gerrit Jan et al. |
| 3 | US 6131580 A | 2000101 7 | Templat e imprint ed materia ls by RFGD plasma deposit ion | 128/898 | Ratner, Buddy D. et al. |
| 4 | US 5455108 A | 1995100 3 | Coated polymer ic fabric having reduced adsorpt ion of protein | 442/126 | Quincy, III, Roger B. et al. |
| 5 | US 5364662 A | 1994111 5 | Surface treatme nt of silicon e rubber | 427/536 | Domenic o, Edward D. et al. |

Ab Silicon Rubber - plasma treated in H_2 or N_2 or He , Ne , Ar (O-free)
graph covalent attachment, ex- bioactive

* (D) A reactor ... react to 250-300 mtorr, then bring back to 1 atm by intro of plasma gas

L19

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|--------------|--------------------|------------|---|------------|-----------------------------|
| 1 | US 2003008 2412 A1 | 20030501 | Method for forming thin film, article having thin film, optical film, dielectric coated electrode, and plasma discharge processor | 428/697 | Fukuda, Kazuhir o et al. |
| 2 | US 2003007 2891 A1 | 20030417 | Thin film forming method, optical film, polarizing film and image display method | 427/569 | Murakami, Takashi et al. |
| 3 | US 2002017 6946 A1 | 20021128 | Porous plasma treated sheet material | 427/569 | O'Brien, Jeffrey J. |
| 4 | US 2002017 2779 A1 | 20021121 | Treating cavitated polymeric films with plasma at atmospheric pressure | 427/569 | O'Brien, Jeffrey J. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|--------------|--------------------------|--------------|---|---------------|---------------------------|
| 5 | US 2002016 8466 A1 | 2002111 4 | System and process for solid-state deposition and consolidation of high velocity powder particles using thermal plastic deformation | 427/180 | Tapphorn, Ralph M. et al. |
| L20 6 | US 2002012 2896 A1 | 2002090 5 | Capillary discharge plasma apparatus and method for surface treatment using the same | 427/569 | Kim, Steven et al. |
| L20 7 | US 2002010 6500 A1 | 2002080 8 | Plasma curing process for porous low-k materials | 428/304 .4 | Albano, Ralph et al. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|--|------------|--|------------|--------------------------|
| 8 | US 6583064 B2 <i>DRAM cell</i> | 20030624 | Low contamination high density plasma etch chamber s and methods for making the same | 438/710 | Wicker, Thomas E. et al. |
| 9 | US 6548123 B1 <i>vac cell</i> | 20030415 | Method for coating a plastic container with vacuum vapor deposition | 427/566 | Plester, George et al. |
| 10 | US 6472076 B1 <i>operation cell</i> | 20021029 | Deposition of organosilsesquioxane films | 428/447 | Hacker, Nigel P. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|---------------|---------------|------------|---|------------|-------------------------|
| 11 | US 6417071 B2 | 20020709 | Sub-atmospheric pressure thermal chemical vapor deposition (SACVD) trench isolation method with attenuated surface sensitivity | 438/424 | Jang, Syun-Ming |
| 12 | US 6403490 B1 | 20020611 | Method of producing a plasma by capacitive-type discharge with a multiple barrier, and apparatus for implementing such a method | 438/710 | Lagarde, Thierry et al. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|--------|--------------|------------|--|------------|----------------------------|
| 120 13 | US 6159531 A | 20001212 | Coating having biological activity and medical implant having surface carrying the same and method | 427/2.24 | Dang, Mai Huong et al. |
| 14 | US 6130397 A | 20001010 | Thermal plasma annealing system, and annealing process | 219/121.37 | Arai, Michio |
| 15 | US 5993917 A | 19991130 | Method and apparatus for improving wettability of foam | 427/536 | Pan, Alfred I-Tsung et al. |
| 16 | US 5968611 A | 19991019 | Silicon nitrogen-based films and method of making the same | 427/579 | Kaloyeros, Alain E. et al. |

L20

| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|---|------------|---|------------|--------------------------|
| 17 | US 5843789 A | 19981201 | Method of analysis of genomic biopolymer and porous materials for genomic analyses | 436/164 | Nomura, Hiroshi et al. |
| 18 | <i>Vac cell</i> US 5616368 A | 19970401 | Field emission devices employing activated diamond particle emitter s and methods for making same | 427/535 | Jin, Sungho et al. |
| 19 | <i>open cell sensor</i> US 5587207 A | 19961224 | Arc assisted CVD coating and sintering method | 427/571 | Gorokhovsky, Vladimir I. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|------------------------------|------------|---|------------|--------------------------|
| 20 | US 5547716 A | 19960820 | Laser absorption wave deposition process and apparatus | 427/577 | Thaler, Stephen L. |
| 21 | US 5510151 A <i>Solar</i> | 19960423 | Continuous film-forming process using microwave energy in a moving substrate web functioning as a substrate and plasma generating space | 427/509 | Matsuyama, Jinsho et al. |
| 22 | US 5470784 A <i>Solar</i> | 19951128 | Method of forming semiconducting materials and barrier s using a multiple chamber arrangement | 438/61 | Coleman, John H. |

| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|--------------------------------------|------------|--|------------|-------------------------------|
| 23 | US 5441765 A <i>photo voltaic</i> | 19950815 | Method of forming Si-O containing coatings | 427/228 | Ballance, David S. et al. |
| 24 | US 5409743 A | 19950425 | PECVD process for forming BPSG with low flow temperature | 427/579 | Bouffard, Mark D. et al. |
| 25 | US 5366770 A | 19941122 | Aerosol-plasma deposition of films for electronic cells | 505/477 | Wang, Xingwu |
| 26 | US 5324553 A | 19940628 | Method for the improved microwave deposition of thin films | 427/571 | Ovshinsky, Stanford R. et al. |
| 27 | US 5260105 A | 19931109 | Aerosol-plasma deposition of films for electrochemical cells | 427/576 | Wang, Xingwu |

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|--------------|------------|--|------------|---------------------------|
| 28 | US 5192717 A | 19930309 | Process for the formation of a polycrystalline semiconductor film by microwave plasma chemical vapor deposition method | 438/479 | Kawakami, Soichiro et al. |
| 29 | US 5143748 A | 19920901 | Timber surface improving treatment process | 427/569 | Ishikawa, Hiroyuki et al. |
| 30 | US 5017308 A | 19910521 | Silicon thin film and method of producing the same | 252/501.1 | Iijima, Shigeru et al. |

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|--------------|------------|--|------------|-----------------------|
| 31 | US 4792460 A | 19881220 | Method for production of polysilanes and polygermanes, and deposition of hydrogenated amorphous silicon, alloys thereof, or hydrogenated amorphous germanium | 427/563 | Chu, Ting L. et al. |
| 32 | US 4743258 A | 19880510 | Polymer materials for vascular prostheses | 623/1.49 | Ikada, Yoshito et al. |
| 33 | US 4537795 A | 19850827 | Method for introducing sweep gases into a glow discharge deposition apparatus | 427/569 | Nath, Prem et al. |

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|---------------|---------------------------------|---------------------|---|------------|----------------------|
| 34 | US 4527007 A | 19850702 | Process for forming passivation film on photoelectric conversion device and the device produced thereby | 136/256 | Fuse, Mario |
| 35 | US 4485121 A | 19841127 | Method for producing a fluorine-containing amorphous semiconductor | 438/483 | Matsumura, Hideki |
| 36 | US 4481229 A | 19841106 | Method for growing silicon-including film by employing plasma deposition | 427/571 | Suzuki, Keizo et al. |
| 37 | US 4439463 A | 19840327 | Plasma assisted deposition system | 427/563 | Miller, Stephen C. |

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| | Document ID | Issue Date | Title | Current OR | Inventor |
|----|--------------|------------|---|------------|-------------------------------|
| 38 | US 4382099 A | 19830503 | Dopant predeposition from high pressure plasma source | 438/57 | Legge, Ronald N. et al. |
| 39 | US 4226898 A | 19801007 | Amorphous semiconductors equivalent to crystal line semiconductors produced by a glow discharge process | 438/483 | Ovshinsky, Stanford R. et al. |
| 40 | US 4226897 A | 19801007 | Method of forming semiconducting materials and barriers | 438/96 | Coleman, John H. |

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(A10) improved porous filter

| | Document ID | Issue Date | Title | Current OR | Inventor |
|---|--------------|------------|--|------------|------------------------|
| 5 | US 5843789 A | 19981201 | Method of analysis of genomic biopolymer and porous materials for genomic analysis | 436/164 | Nomura, Hiroshi et al. |
| 6 | US 4743258 A | 19880510 | Polymer materials for vascular prostheses | 623/1.49 | Ikada, Yoshito et al. |

(B2) nucleic acid filter

(D8) method of sample formation

(P16) PTFE gas plasma at 100 mtorr

← agent at to lab

★

(B3) Vascular prosthesis for porous PTFE ...

(B8) It is oxygen - little protein adsorption

(B15) A wide range of PTFE

(D6) A commercial corona discharge at 1 atm

(P11) ... prosthesis measured

(L2e)

| | Document ID | Issue Date | Title | Current OR | Inventor |
|---|--|------------|--|------------|--------------------------|
| 1 | US 20030072891 A1 <i>L. X. all</i> <i>PTFE electrical conduct</i> | 20030417 | Thin film forming method, optical film, polarizing film and image display method | 427/569 | Murakami, Takashi et al. |
| 2 | US 20020122896 A1 <i>[0002] present Im-planer at latum</i> <i>[0005] PTFE not in present</i> | 20020905 | Capillary discharge plasma apparatus and method for surface treatment using the same | 427/569 | Kim, Steven et al. |
| 3 | US 20020106500 A1 <i>[0019] sub list... PTFE</i> <i>[0020] ... photo voltaic cells</i> | 20020808 | Plasma curing process for porous low-k materials | 428/304.4 | Albano, Ralph et al. |
| 4 | US 6159531 A <i>pull</i> <i>exactly 1 yr ↓</i> | 20001212 | Coating having biological activity and medical implant having surface carrying the same and method | 427/2.24 | Dang, Mai Huong et al. |

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